

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Jae-Yong CHO, et al.

Application No.:

Group Art Unit:

Filed: April 14, 2004

Examiner:

For: ELECTROSTATIC CHUCK

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure provisions of 37 CFR § 1.56, there is hereby provided certain information which the Examiner may consider material to the examination of the subject U.S. patent application. It is requested that the Examiner make this information of record if it is deemed material to the examination of the subject application.

1. Enclosures accompanying this Information Disclosure Statement are:

- 1a. ☒ Form PTO-1449.
- 1b. ☒ Copies of IDS citations.
- 1c. ☐ An English language copy of search report(s) from a counterpart foreign application or a PCT International Search Report.
- 1d. ☐ English language translation (complete or relevant portion(s)) attached to each non-English language publication.
- 1e. ☒ Explanations of Relevancy of References (ATTACHMENT 1(e), hereto) for providing a concise explanation of each non-English publication.

2. ☒ In accordance with 37 CFR § 1.98, a concise explanation of what is presently understood to be the relevance of each non-English language publication is

(Check appropriate Items 2a, 2b, 2c and/or 2d)

- 2a. ☐ satisfied because all non-English language publications were cited on the enclosed "English-language version of the search report or action which indicates the degree of relevance found by the foreign office". (See MPEP 609, Minimum Requirements for an Information Disclosure Statement, Part A(3): Concise Explanation of Relevance, pp. 600-100 to 600-101, Rev. 1, Feb. 2000.)
- 2b. ☐ set forth in the application.

- 2c. ☐ satisfied because an English language translation (complete or relevant portion(s)) is attached to each non-English language publication.
- 2d. ☒ enclosed as Attachment 1(e), hereto.
3. No admission is made that the information cited in this Statement is, or is considered to be, material to patentability nor a representation that a search has been made (other than search report(s) from a counterpart foreign application or a PCT International Search Report, if submitted herewith). 37 CFR §§ 1.97(g) and (h).

Respectfully submitted,

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FORM PTO-1449 <div style="text-align: center;">U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</div> <div style="text-align: center;">LIST OF REFERENCES CITED BY APPLICANT</div> <div style="text-align: center;"><i>(Use several sheets if necessary)</i></div>	ATTORNEY DOCKET NO. 1572.1258	APPLICATION NO.
FIRST NAMED INVENTOR Jae-Yong CHO, et al.		
FILING DATE April 14, 2004		GROUP ART UNIT

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NO.	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO
	AG	KR 10-303076	7/9/01	Korea				X
	AH	KR 10-313028	10/16/01	Korea				X
	AI	KR 2001-46528	6/15/01	Korea				X
	AJ	JP 2002-223366	8/9/02	Japan				X
	AK	JP 2000-36490	2/2/00	Japan				X
	AL							

OTHER REFERENCES (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

			TRANSLATION	
			YES	NO
	AM			
	AN			
	AO			
EXAMINER			DATE CONSIDERED	
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.				

ATTACHMENT 1(e)

EXPLANATIONS OF RELEVANCY OF REFERENCES	ATTORNEY DOCKET NO. 1572.1258	APPLICATION NO.
	FIRST NAMED INVENTOR Jae-Yong CHO, et al.	
	FILING DATE April 14, 2004	GROUP ART UNIT

Reference AG (KR 10-303076) is entitled "Substrate Support with Pressure Zones Having Reduced Contact Area and Temperature Feedback".

Reference AH (KR 10-313028) is entitled "Plasma Processing Method and Apparatus".

Reference AI (KR 2001-46528) is entitled "Structure for Cooling of Electro Static Chuck".

Reference AJ (JP 2002-223366) is entitled "Image Processing Method and System Thereof".

Reference AK (JP 2000-36490) is entitled "Production of Bulky Paper".